

Supporting Information

High-performance organic field-effect transistors based on organic single crystal microribbons fabricated by an *in situ* annealing method[†]

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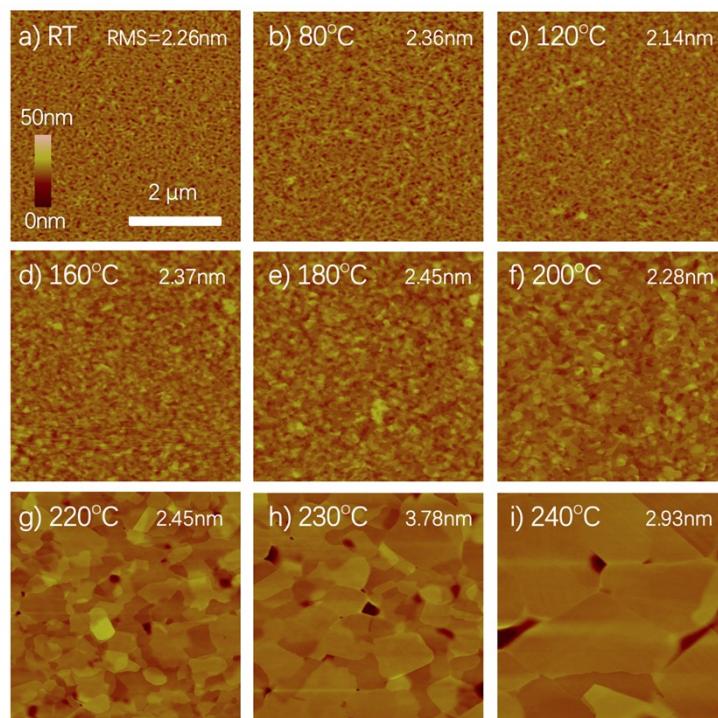


Fig. S1 AFM images of 35 nm NBTBT-6 film after annealing at different temperatures (the value at top right corner in each image indicates the root mean square (RMS) roughness, respectively).

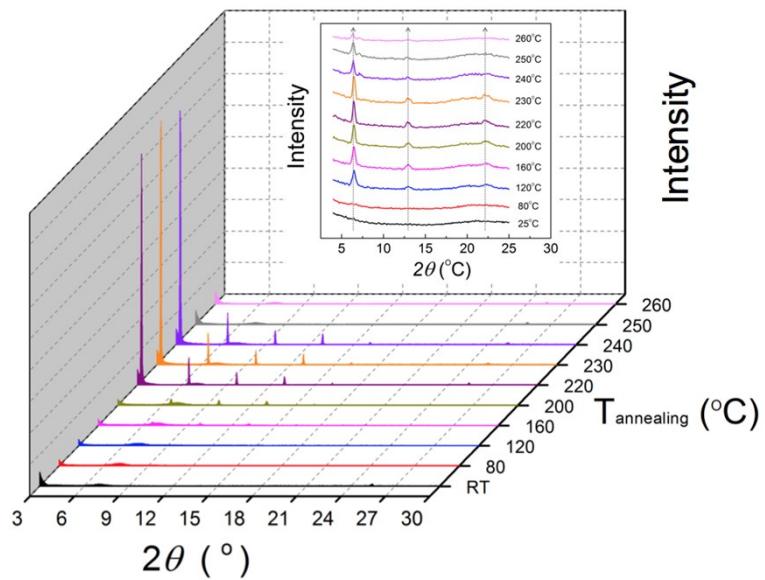


Fig. S2 Out-of-plane XRD (inset: in-plane XRD) diffractograms of 35nm NBTBT-6 film after annealing at different temperature.

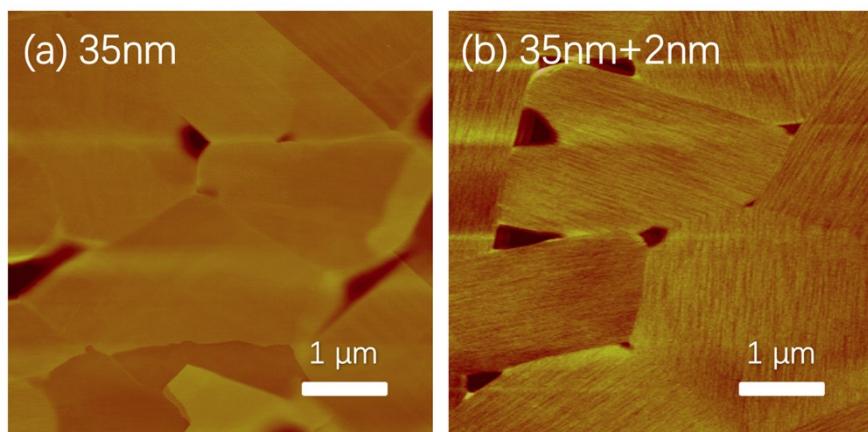


Fig. S3 AFM images of (a) 35nm NBTBT-6 film after annealing at 240°C and (b) 35nm NBTBT-6 film after annealing at 240°C, followed by vapor-deposition of 2nm NBTBT-6 thin film (1~2 layers).

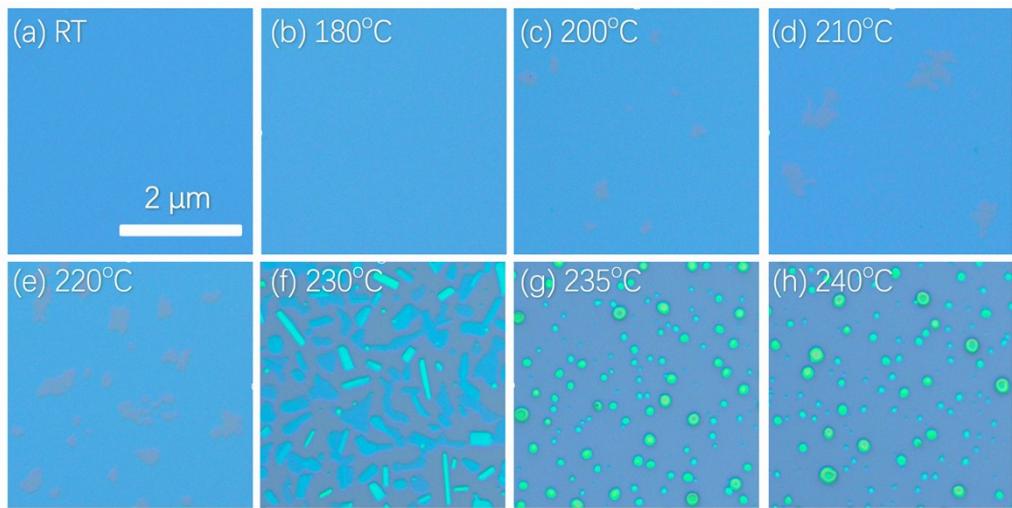


Fig. S4 Microphotographs of 2nm NBTBT-6 film after annealing at different temperatures.

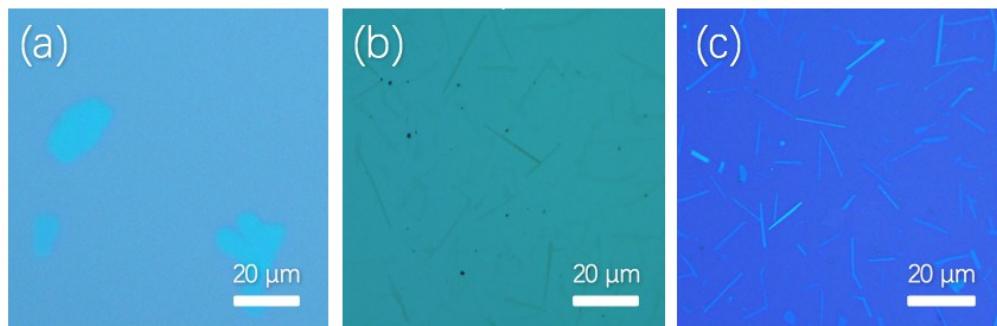


Fig. S5 Microphotographs of 2nm NBTBT-6 film after annealing at 230°C on different substrates: (a) SiO₂ (b) OTS-modified auto-oxidized SiO₂ (~1nm) (c) OTS-modified 300nm SiO₂.

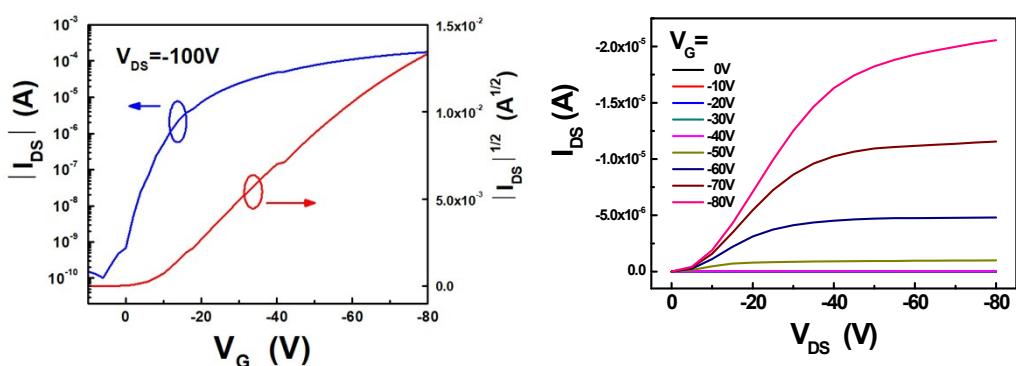


Fig. S6 The transfer and output curves of OFETs based on the vapor-grown thin films.

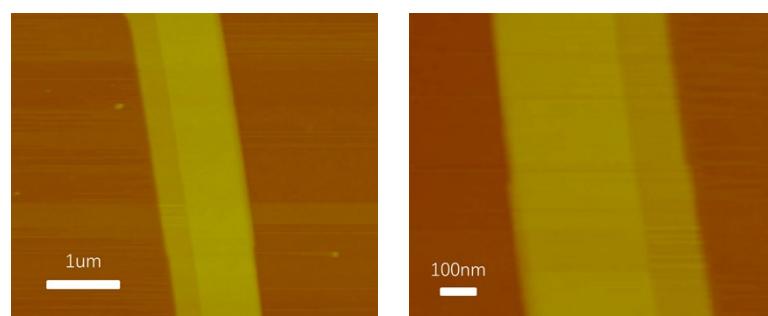


Fig. S7 Microphotographs of two NBTBT-6 microribbons.